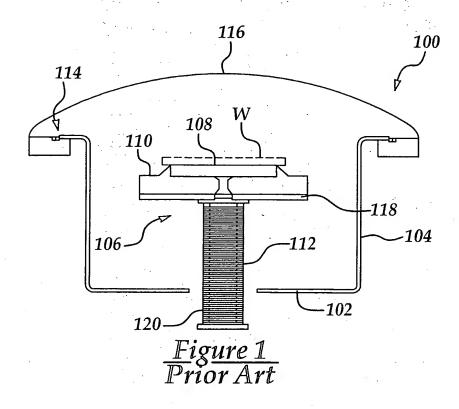
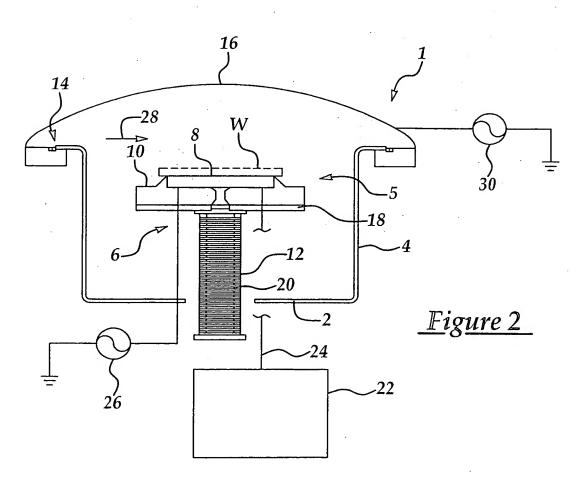
Inventor: SHING-CHYANG PAN
Serial No.: To Be Assigned Filed: Herewith
For: Pre-Clean Chamber With Wafer Heating Apparatus and Method of Use
Attorney Doc. No.: 67,200-1226





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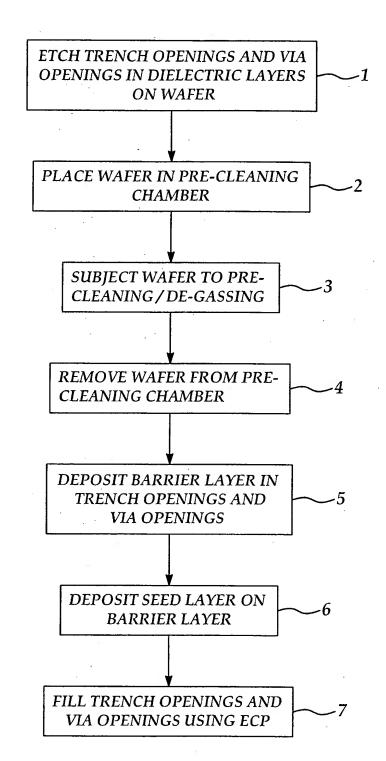


Figure 3